

III-Vs for CMOS Beyond Silicon

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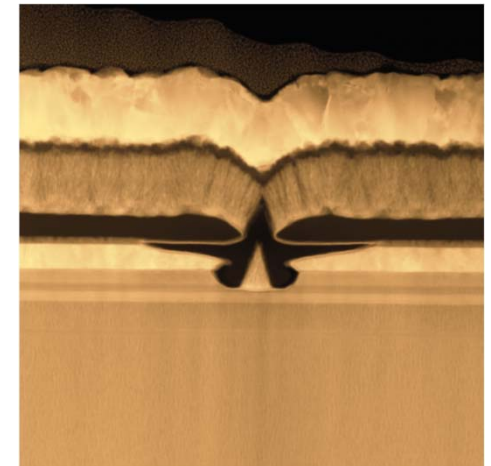
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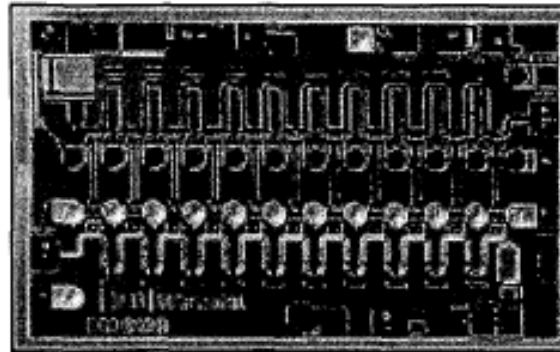
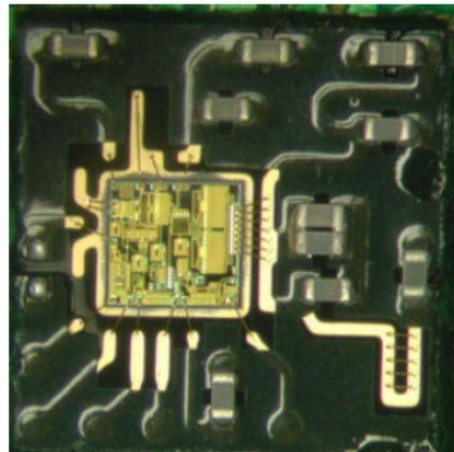


III-V HEMT Electronics Today

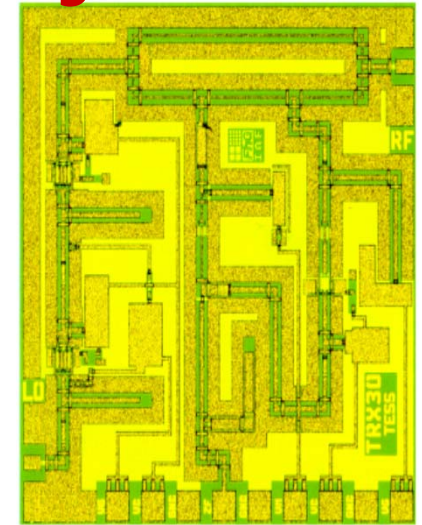


TriQuint and Skyworks Power iPhone 5

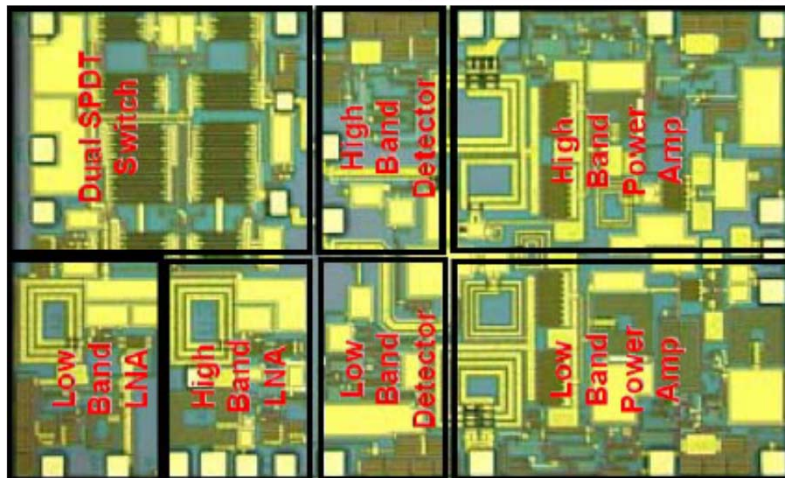
UMTS-LTE PA module
Chow, MTT-S 2008



40 Gb/s modulator driver
Carroll, MTT-S 2002

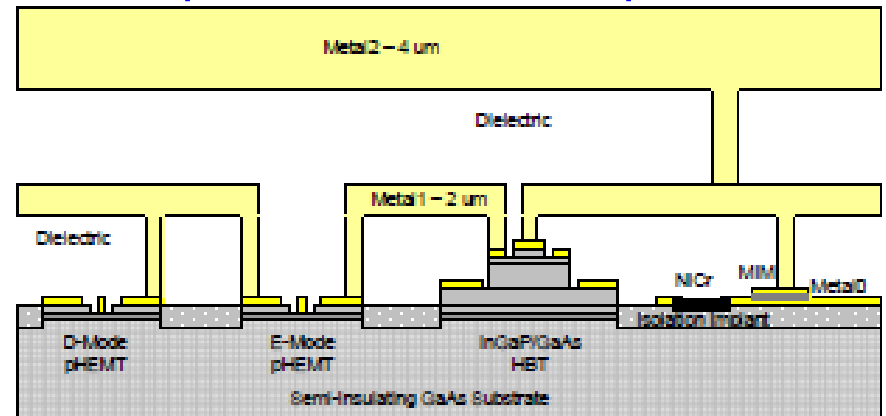


77 GHz transceiver
Tessmann, GaAs IC
1999



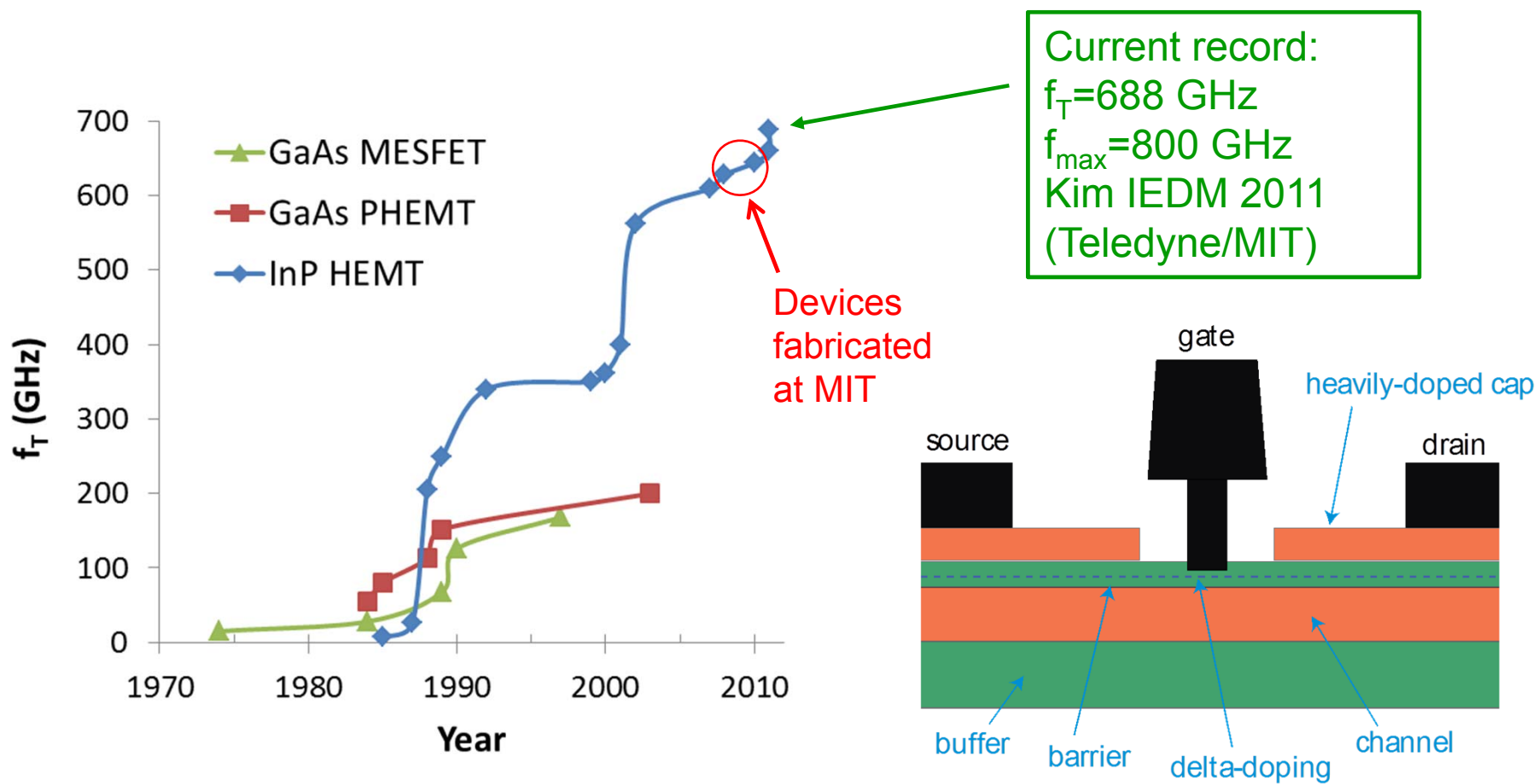
Single-chip WLAN MMIC, Morkner, RFIC 2007

Bipolar/E-D PHEMT process



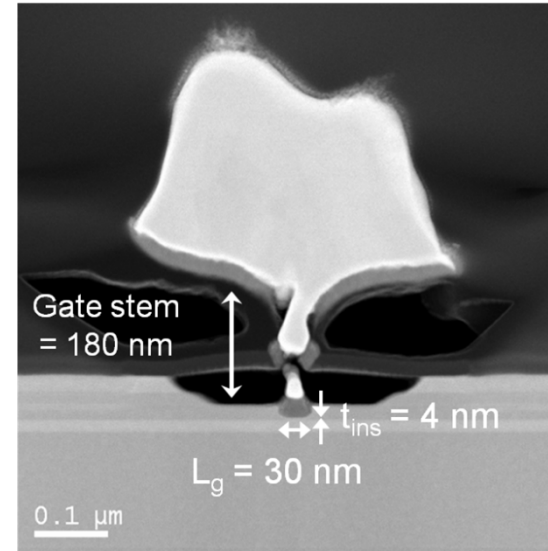
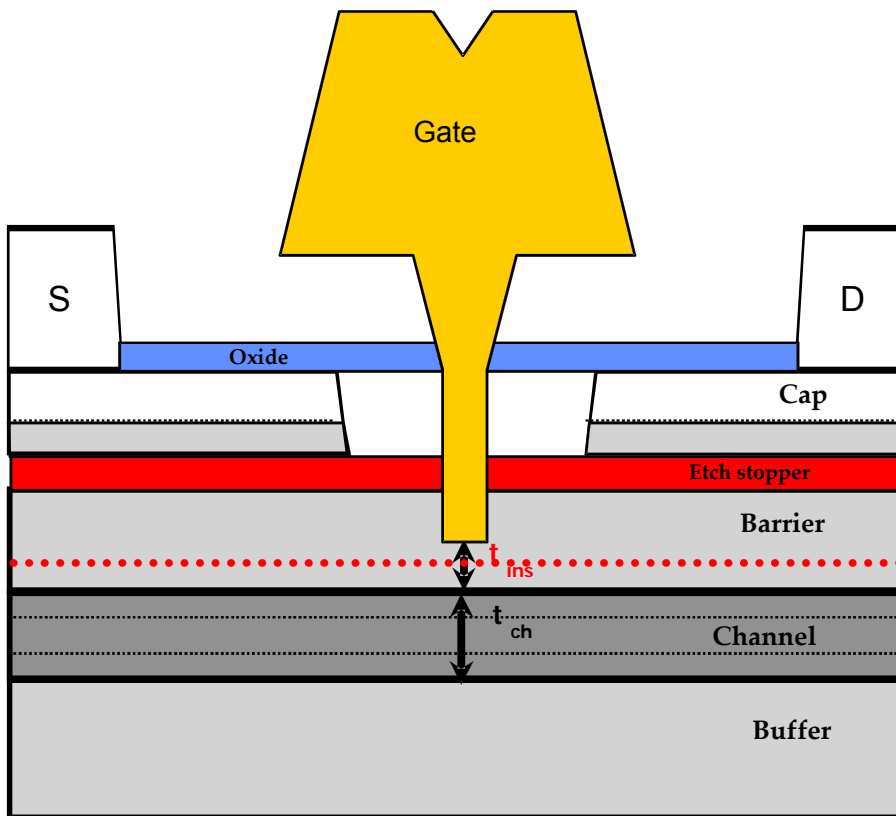
Henderson, Mantech 2007

III-V HEMT: record f_T vs. time



- For >20 years, record f_T obtained on InGaAs-channel HEMTs
- InGaAs-channel HEMTs offer record balanced f_T and f_{max}

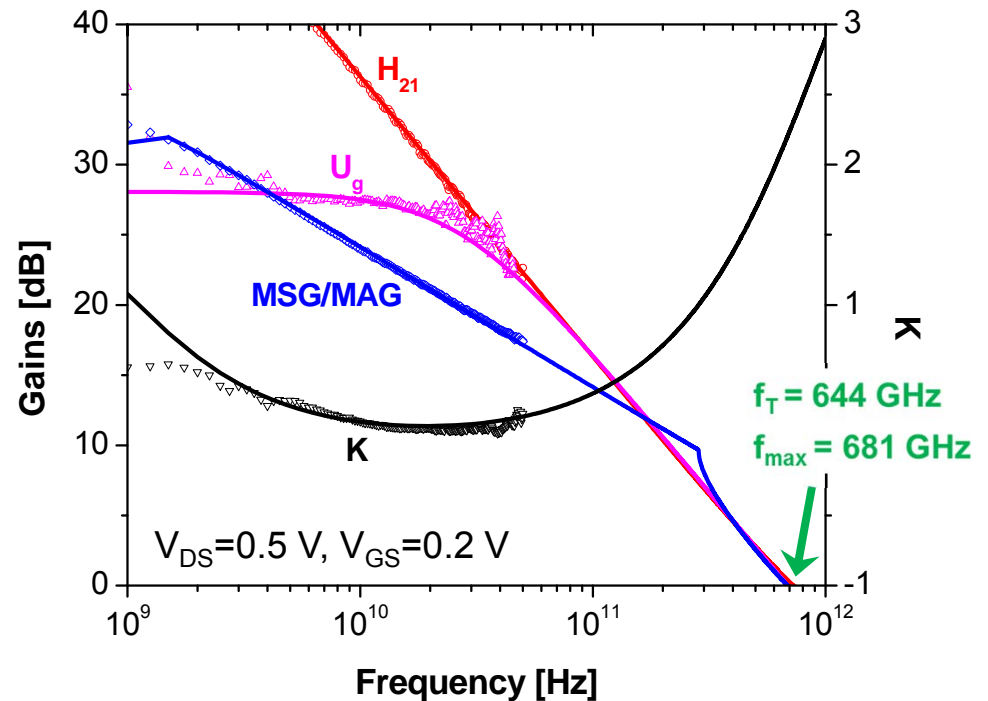
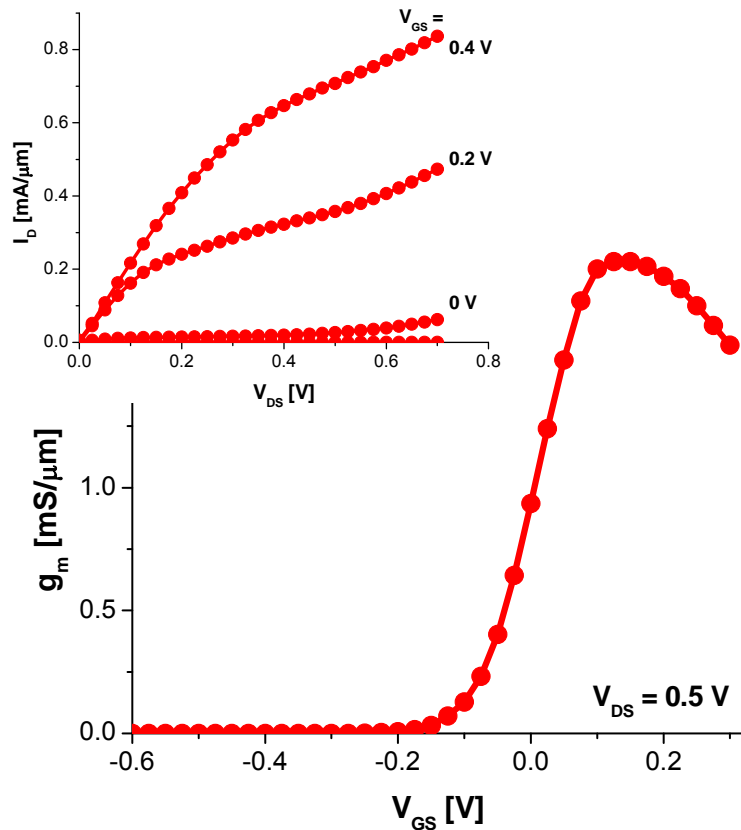
InAlAs/InGaAs HEMTs at MIT



- QW channel ($t_{ch} = 10$ nm):
 - InAs core
 - InGaAs cladding
- $\mu_{n,Hall} = 13,200$ cm²/V-sec
- InAlAs barrier ($t_{ins} = 4$ nm)
- $L_g = 30$ nm

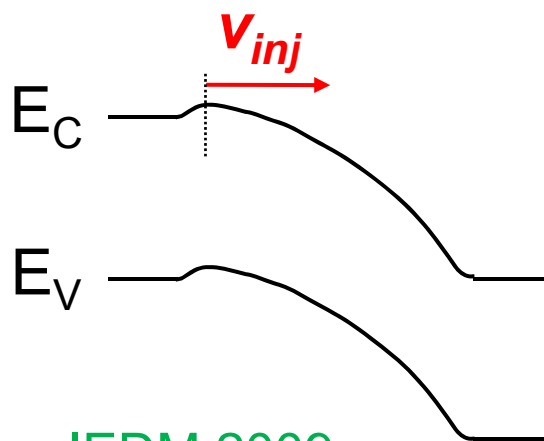
$L_g = 30$ nm InGaAs HEMT

Kim, EDL 2010

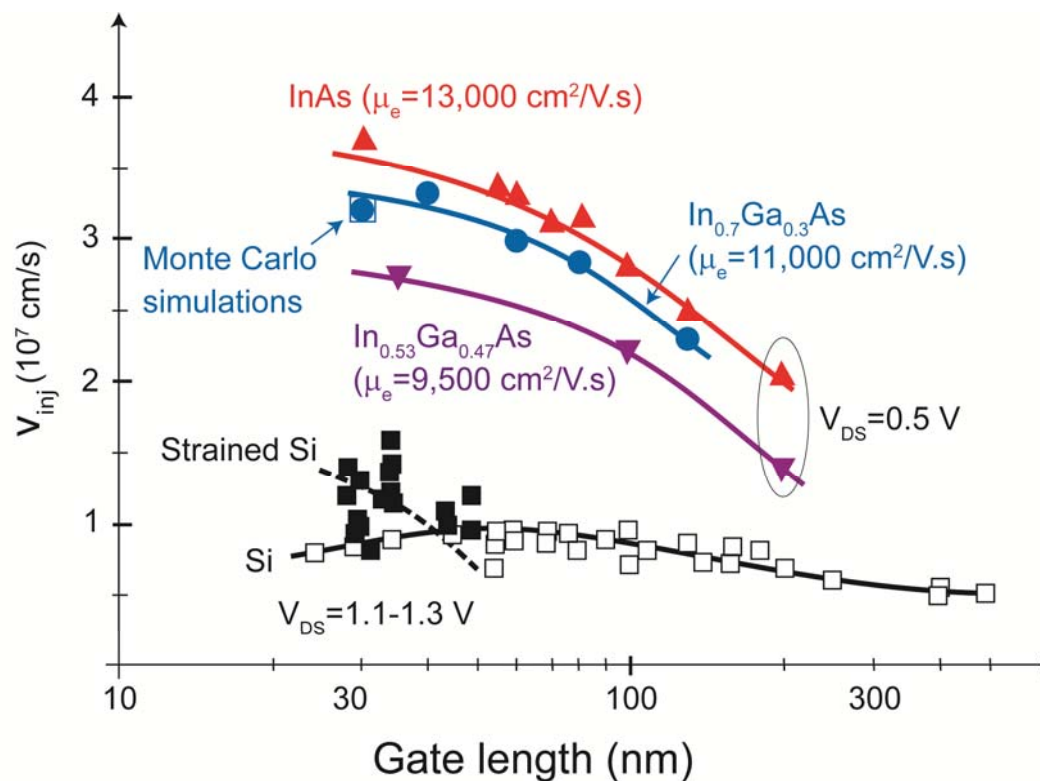


- High transconductance: $g_{mpk} = 1.9$ mS/ μm at $V_{DD} = 0.5$ V
- First transistor of any kind with both f_T and $f_{max} > 640$ GHz
(current record is $f_T, f_{max} > 688$ GHz in Teledyne/MIT collaboration)

InGaAs Electron Injection Velocity



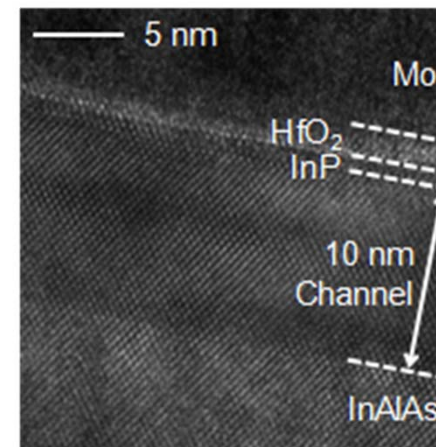
Kim, IEDM 2009
Liu, Springer 2010
Khakifirooz, TED 2008
del Alamo, Nature 2011



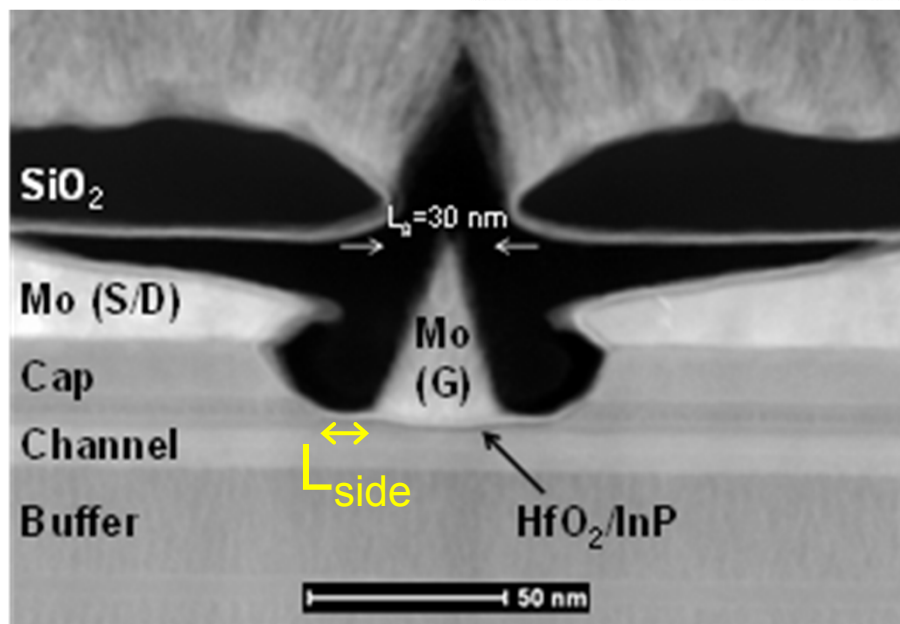
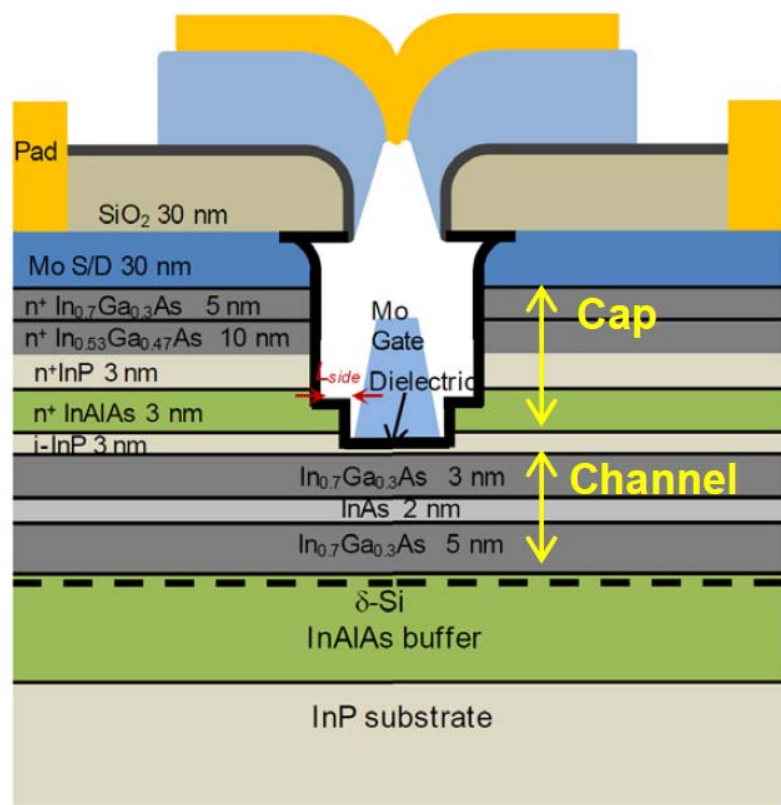
- $v_{inj}(\text{InGaAs})$ increases with InAs fraction in channel
- $v_{inj}(\text{InGaAs}) > 2v_{inj}(\text{Si})$ at less than half V_{DD}
- $\sim 100\%$ ballistic transport at $L_g \sim 30$ nm

Self-Aligned InGaAs QW-MOSFETs

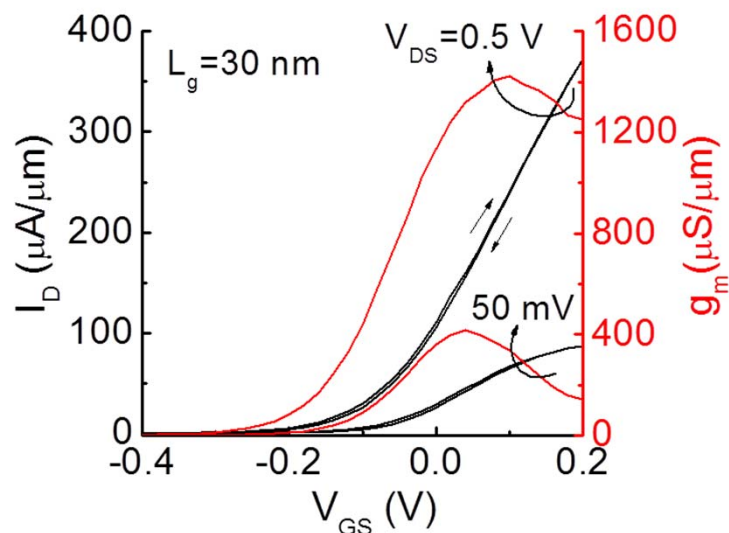
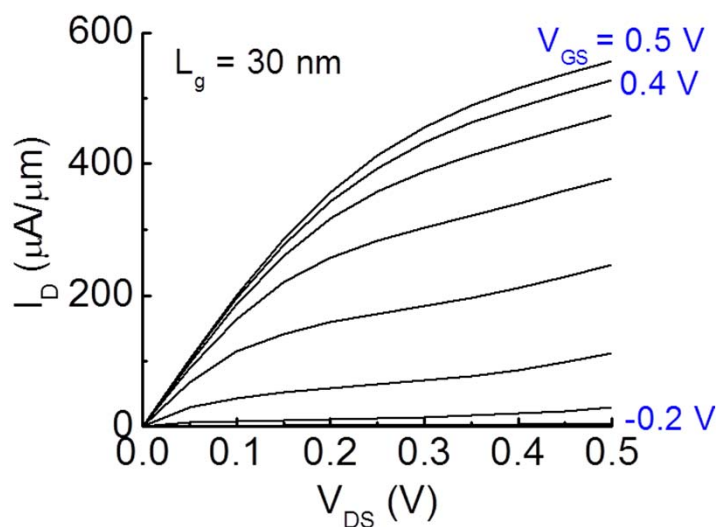
- Scaled barrier (InP: 1 nm + HfO₂: 2 nm) [EOT~0.8 nm]
- 10 nm thick channel with InAs core
- Tight S/D spacing ($L_{\text{side}} = 20\sim 30$ nm)
- Process designed to be compatible with Si fab



Lin, IEDM 2012

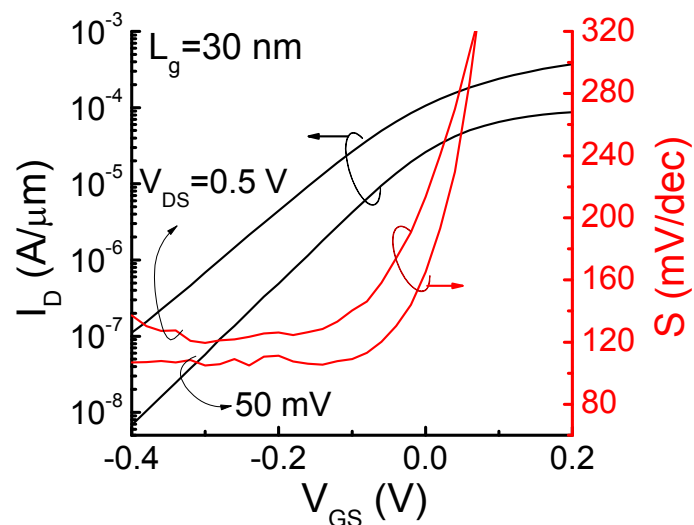


$L_g = 30$ nm Self-aligned QW-MOSFET

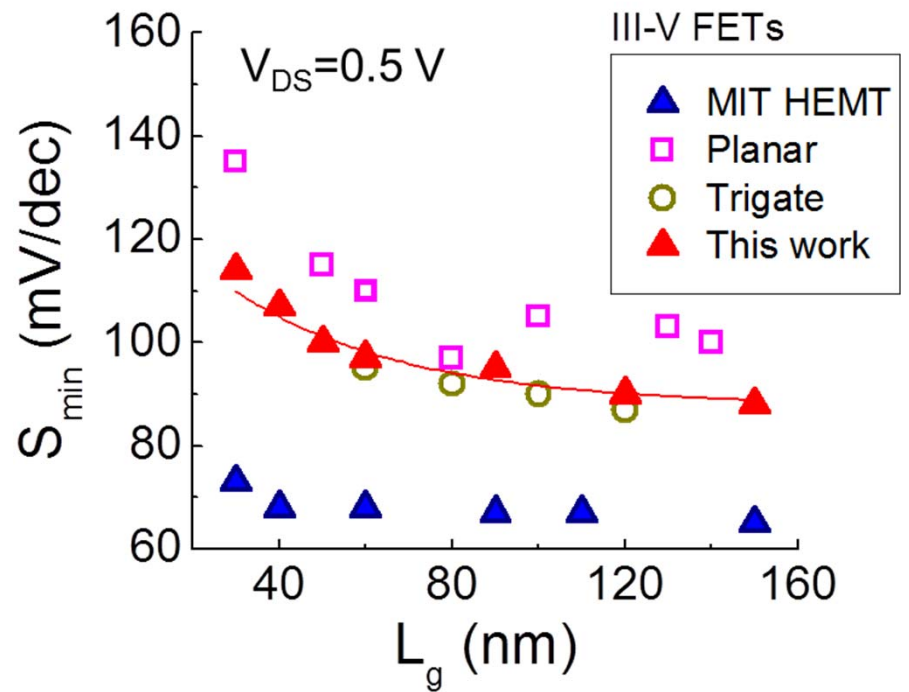
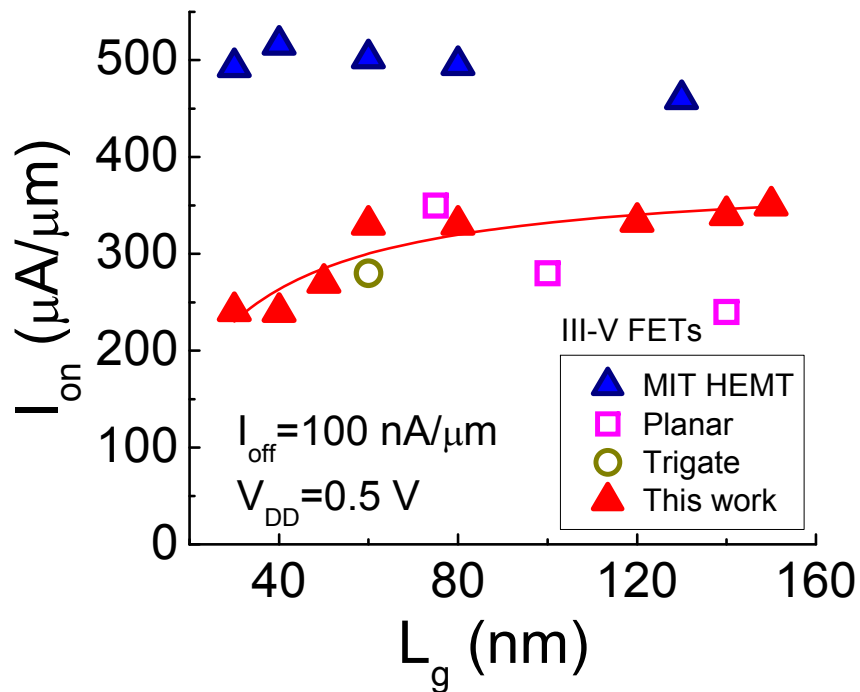


At $V_{DS} = 0.5$ V:

- $g_m = 1.4$ mS/ μm
- $S = 114$ mV/dec
- $I_g < 1$ nA/ μm
- $R_{on} = 470$ $\Omega \cdot \mu\text{m}$



Scaling and benchmarking

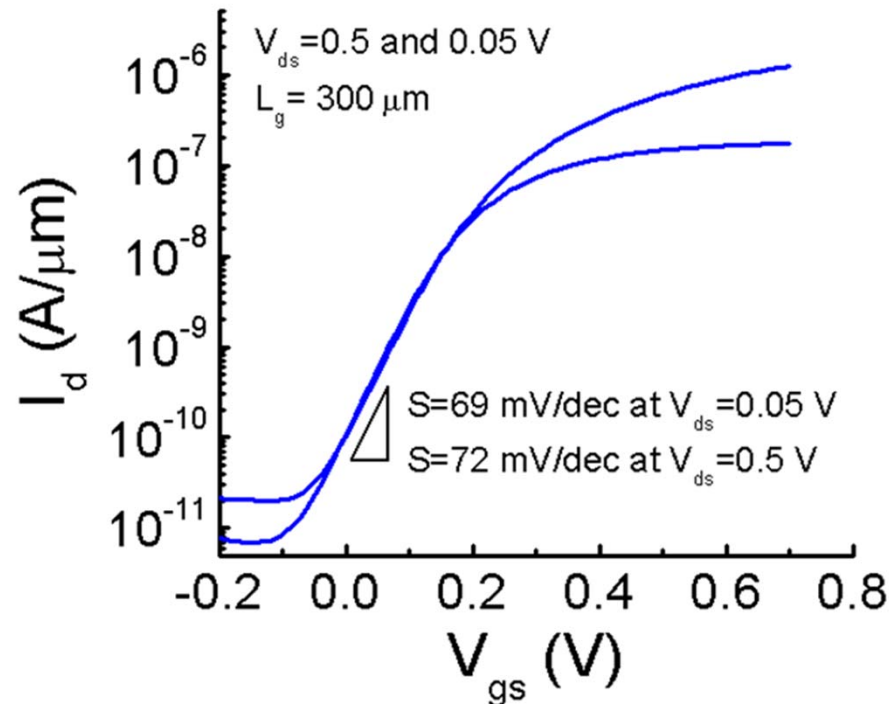


Lin, IEDM 2012

- Superior behavior to any planar III-V MOSFET to date
- Matches performance of III-V Trigate MOSFETs
[Radosavljevic, IEDM 2011]

Long-channel InGaAs MOSFET

InP (1 nm) + Al₂O₃ (0.4 nm) + HfO₂ (2 nm) → EOT~0.9 nm



Lin, IEDM 2012

- $S=69 \text{ mV/dec}$ at $V_{DS}=50 \text{ mV}$
- Close to lowest S reported in any III-V MOSFET: 66 mV/dec (EOT=1.2 nm) [Radosavljevic, IEDM 2011]

Ongoing research

- **N-channel InGaAs MOSFETs:**
 - Planar InGaAs MOSFET with improved access region for reduced resistance
 - Trigate InGaAs MOSFET with self-aligned contacts
 - Nanowire MOSFET with enhanced subthreshold swing
 - Ohmic contacts to InGaAs MOSFET
- **P-channel InGaSb MOSFETs:**
 - Planar InGaSb MOSFET with uniaxial compressive strain for enhanced hole transport
 - Ohmic contacts to InGaSb MOSFET